

# **TFE4146 - Semiconductor Devices - Fall 2023**

## **Problem Set 7**

**Peter Pham**

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## Problem 1

Figure 1 shows the high frequency capacitance vs. voltage ( $C-V$  characteristics) of an n-channel MOSFET, made from p-type Si substrate with a dopant concentration of  $N_a = 5 \cdot 10^{15} \text{ cm}^{-3}$  and use of  $n^+$ -polysilicon gate electrode. The thickness of the oxide in the gate area is  $d_{ox} = 100 \text{ \AA}$ , and the effective interface charge  $Q_i = 4 \cdot 10^{10} q \text{ [Ccm}^{-2}\text{]}$ . Assume room temperature:  $T = 295 \text{ K}$ .

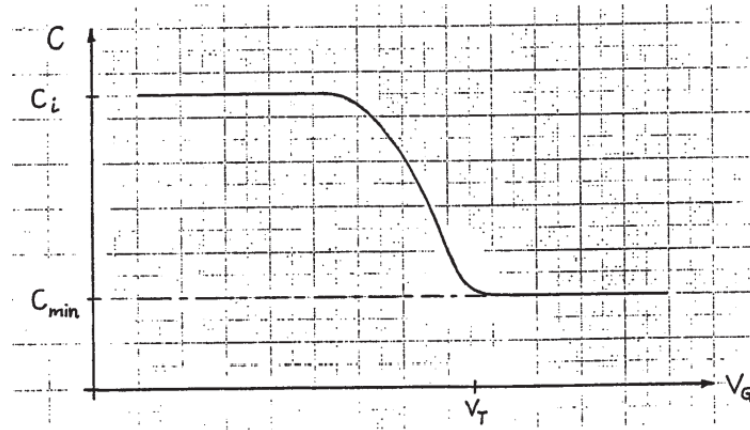


Figure 1: High frequency capacitance vs. voltage of an n-channel MOSFET

a) A MOSFET of this kind has two contributions to the capacitance:  $C_i$  and  $C_s$ . Describe the mechanisms behind these two contributions, draw an equivalent circuit diagram for the MOS capacitance and find an expression for  $C_{\min}$  expressed by  $C_i$  and  $C_s = C_{d,\min}$  (assuming that the component at hand is biased in strong inversion).

We start by describing the two capacitance:

- The insulator capacitance  $C_i$ :

This capacitance is given by  $C_i = \frac{\epsilon_i}{d}$  where  $\epsilon_i$  is the permittivity of the insulator, while  $d$  is the insulator thickness. This capacitance is associated with the metal-oxide part of the mos structure. It behaves a lot like a parallel-plate capacitor as the oxide layer functions as the dielectric, and the capacitance is determined by the permittivity of the oxide material and the thickness of the oxide layer.

- The voltage-dependent semiconductor capacitance  $C_s$ :

This capacitance is given by  $C_s = \frac{qQ}{qV} = \frac{dQ_s}{d\phi_s}$  where  $Q_s$  is the space charge density per unit area and  $\phi_s$  is the surface potential. This capacitance arise from the formation of a

space-charge region within the semiconductor when a voltage is applied. For less negative voltage the accumulation of electrons at the surface makes the semiconductor surface become depleted and a depletion-layer capacitance is added in series with  $C_i$

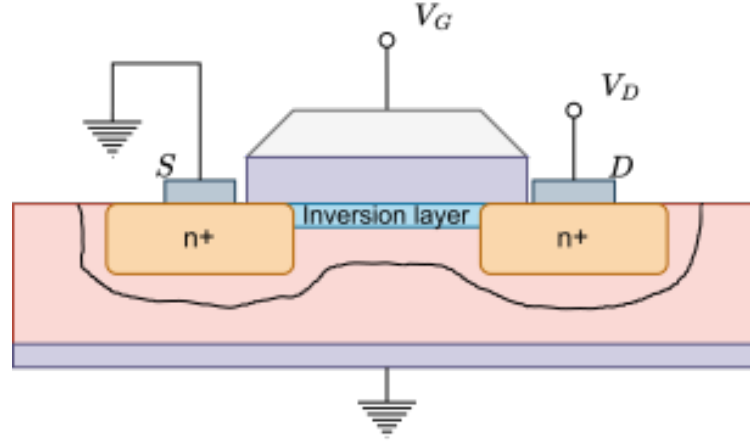


Figure 2: Circuit diagram for the MOS capacitance

The minimum MOS capacitance  $C_{min}$  is given by

$$C_{min} = \frac{C_i C_{d,min}}{C_i + C_{d,min}}$$

as  $C_s = C_{d,min}$  we get

$$C_{min} = \frac{C_i C_s}{C_i + C_s}$$

**b) Determine a numerical value for the capacitance of the MOS structure at hand operating at a negative gate voltage ( $V_G \ll V_T$ ) and positive gate voltage ( $V_G \gg V_T$ ), respectively.**

For the case ( $V_G \ll V_T$ ):

$$C = C_i = \frac{\epsilon_i}{d}$$

as the relative permittivity  $\epsilon_r$  for silicon dioxide is 3.9 and permittivity of free space  $\epsilon_0 = 8.85 \cdot 10^{-14} \frac{F}{cm}$  this gives us:

$$C = \frac{3.9 \cdot 8.85 \cdot 10^{-14}}{10^{-6}} = 3.4515 \cdot 10^{-7}$$

For the case ( $V_G \gg V_T$ ):

$$C = C_{min} = \frac{C_i C_s}{C_i + C_s}$$

where  $C_s = \frac{\epsilon_s}{W_m}$ . We start by calculating  $W_m$

$$W_m = 2 \left[ \frac{\epsilon_s \phi_F}{q N_a} \right]^{1/2}$$

where  $\phi_F$  is given by

$$\phi_F = \frac{kT}{q} \ln \frac{N_a}{n_i} = \frac{1.38 \cdot 10^{-23} \cdot 295}{1.6 \cdot 10^{-19}} \ln \frac{5 \cdot 10^{15}}{1.5 \cdot 10^{10}} = 0.324 eV$$

this gives

$$W_m = 2 \left[ \frac{11.68 \cdot 8.85 \cdot 10^{-14} \cdot 0.324}{1.6 \cdot 10^{-19} \cdot 5 \cdot 10^{15}} \right]^{1/2} = 4.1 \cdot 10^{-5} cm$$

$$\Rightarrow C_s = \frac{11.68 \cdot 8.85 \cdot 10^{-14}}{4.1 \cdot 10^{-5}} = 2.52 \cdot 10^{-8}$$

and we end up with

$$C = \frac{3.4515 \cdot 10^{-7} \cdot 2.52 \cdot 10^{-8}}{3.4515 \cdot 10^{-7} + 2.52 \cdot 10^{-8}} = 2.35 \cdot 10^{-8} \frac{F}{cm^2}$$

**c) Draw a sketch that shows how the  $C - V$  characteristics in the figure above changes for low frequencies (typical  $\sim 1 - 100$  Hz ), and explain the reason for this characteristic change in the  $C - V$  characteristics.**

Given:

- Intrinsic charge carrier density for Si :  $n_i = 1.5 \cdot 10^{10} cm^{-3}$

- Relative dielectric permittivity for Si :  $\epsilon_r = 11.8$
- Relative dielectric permittivity for SiO<sub>2</sub> :  $\epsilon_r = 3.9$

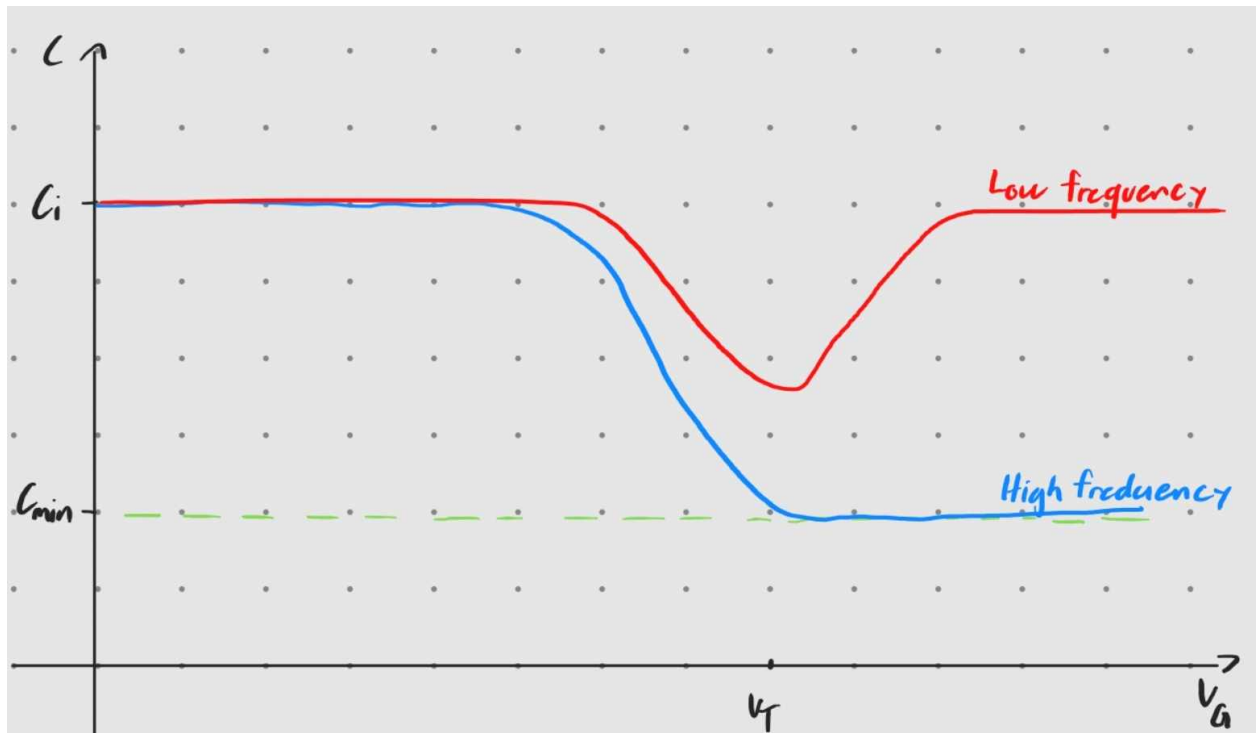


Figure 3: Sketch of the C - V characteristic.

## Problem 2

In this problem we go through the derivation of the most basic mathematical models for the I-V characteristic of a MOSFET. We will first derive the model valid in the triode region and use this to find an expression valid in the saturation (active) region.

a) Draw a cross-section of an NMOS transistor (p-type substrate). Sketch the inversion layer and depletion region when  $V_G > V_T$ ,  $V_S = 0$  and  $V_D = 0$ .

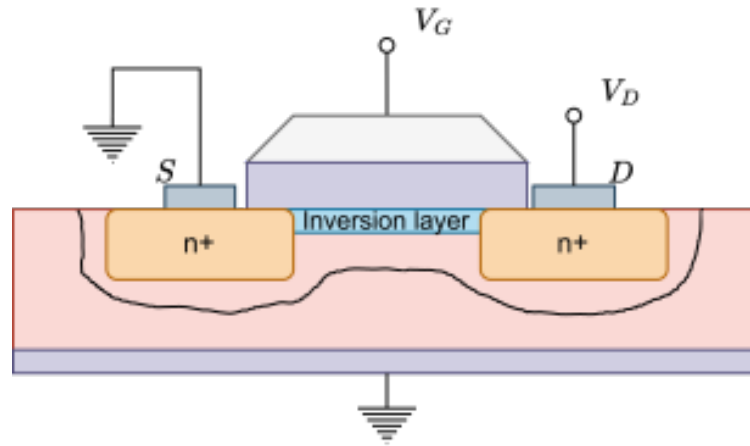


Figure 4: cross-section of an NMOS transistor

b) The contributions of the applied gate-voltage is given by

$$V_G = V_{FB} - \frac{Q_s}{C_i} + \phi_s = V_{FB} - \frac{Q_n + Q_d}{C_i} + \phi_s, \quad (1)$$

where  $V_{FB}$  is the flat-band voltage,  $Q_s$  is the total amount of induced charge in the semiconductor per area,  $C_i$  is the insulator (oxide) capacitance per area, and  $\phi_s$  is the potential at interface between the semiconductor and the insulator. The induced charge  $Q_s$  consists of two contributions, the mobile inversion charge  $Q_n$  and the fixed charge in the depletion region  $Q_d$ .

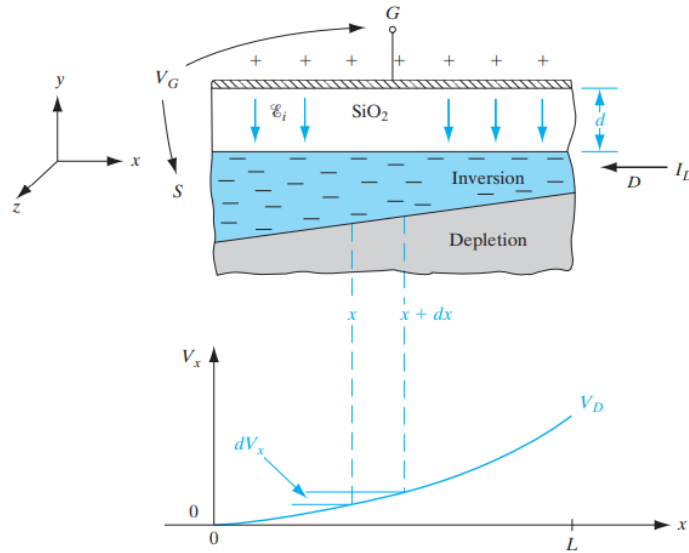


Figure 5: The inverted channel of an NMOS transistor. Figure 6-26 in Streetman.

**Consider figure 5. When  $V_D > 0$ , the surface potential  $\phi_s(x)$ , and hence the inversion charge  $Q_n(x)$ , will no longer be constant throughout the channel, but depend on the potential  $V_x$ . Let  $0 < V_D < (V_G - V_T)$  and use equation 1 to show that**

$$Q_n(x) = -C_i (V_G - V_T - V_x) \quad (2)$$

**when the variations of  $Q_d$  with respect to  $V_x$  is neglected. Discuss the validity of this assumption. Would the variations in  $Q_d$  increase or decrease the  $Q_n$  ?**

Rewriting equation 1

$$Q_n = V_{FB}C_i - Q_d + \phi_s C_i - V_G C_i \quad (3)$$

$$= -C_i \left[ V_G - \left( V_{FB} + \phi_s - \frac{Q_d}{C_i} \right) \right] \quad (4)$$

At threshold, the term in brackets can be written as  $V_G - V_T$ , but with a voltage  $V_D$  applied, there is a voltage rise  $V_x$  from the source to each point  $x$  in the channel.

$$Q_n = -C_i \left[ V_G - V_{FB} - 2\phi_F - V_x - \frac{1}{C_i} \sqrt{2q\epsilon_s N_a (2\phi_F + V_x)} \right] \quad (5)$$

as we neglect the variations of  $Q_d$  with respect to  $V_x$  the equation gets simplified to

$$Q_n(x) = -C_i (V_G - V_T - V_x) \quad (6)$$



**c) The drain current  $I_D$  is given by**

$$I_D = ZQ_n(x)\bar{\mu}_n E_x(x), \quad (7)$$

where  $Z$  is the width of the gate,  $\bar{\mu}_n$  is the surface electron mobility and

$$E_x(x) = -\frac{dV_x}{dx} \quad (8)$$

is the component of the E-field in the  $x$ -direction. Use equations 2 and 8 to show that the drain current in this region is given by

$$I_D = \frac{\bar{\mu}_n Z C_i}{L} \left[ (V_G - V_T) V_D - \frac{1}{2} V_D^2 \right]$$

at point  $x$  we have

$$I_D dx = \bar{\mu}_n Z |Q_n(x)| dV_x \quad (9)$$

If we integrate from source to drain,

$$\begin{aligned} \int_0^L I_D dx &= \bar{\mu}_n Z C_i \int_0^{V_D} (V_G - V_T - V_x) dV_x \\ I_D &= \frac{\bar{\mu}_n Z C_i}{L} \left[ (V_G - V_T) V_D - \frac{1}{2} V_D^2 \right] \end{aligned}$$

d) Sketch the inversion layer and depletion region in the transistor when the drain-voltage is increased such that  $V_D = (V_G - V_T)$ .

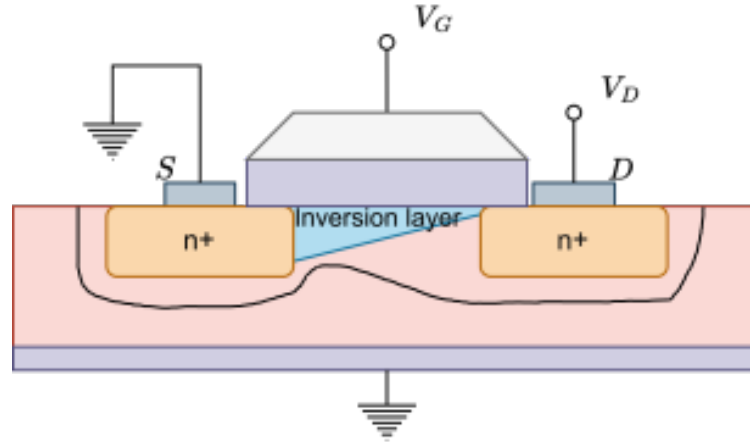


Figure 6: The inversion layer and depletion region in the transistor when the drain-voltage is increased such that  $V_D = (V_G - V_T)$ .

e) The square-law model is the simplest (useful) model describing the drain current of a MOSFET operating in saturation and strong inversion. This model assumes  $I_D$  to be independent of  $V_D$  when  $V_G > V_T$  and  $V_D > (V_G - V_T)$ . Use this assumption to show that this saturation current is given by

$$I_D(\text{ sat. }) = \frac{1}{2} \bar{\mu}_n C_i \frac{Z}{L} (V_G - V_T)^2.$$

the saturation condition is approximately given by

$$V_D(\text{ sat. }) \cong V_G - V_T$$

If we substitute this approximation into we get

$$I_D(\text{ sat. }) \cong \frac{1}{2} \bar{\mu}_n C_i \frac{Z}{L} (V_G - V_T)^2$$

**f) Explain why  $I_D$  may be approximated as independent of  $V_D$  in the saturation region. Explain some of the physical effects we neglect and discuss the validity of this approximation for different values of  $L$  and  $V_D$ .**

As the drain voltage is increased, the voltage across the oxide decreases near the drain, and  $Q_n$  becomes smaller. This results in the channel being pinched off at the drain end, and the current saturates.

The charge  $Q_d$  is often assumed constant and its variation with respect to the channel voltage  $V_x$  is neglected. This is valid as when a MOSFET is in a strong inversion ( $V_G > V_T$ ), the mobile inversion charge  $Q_n$  is much larger than the depletion charge  $Q_d$ .

We can approximate  $L$  for longer channel length(?)